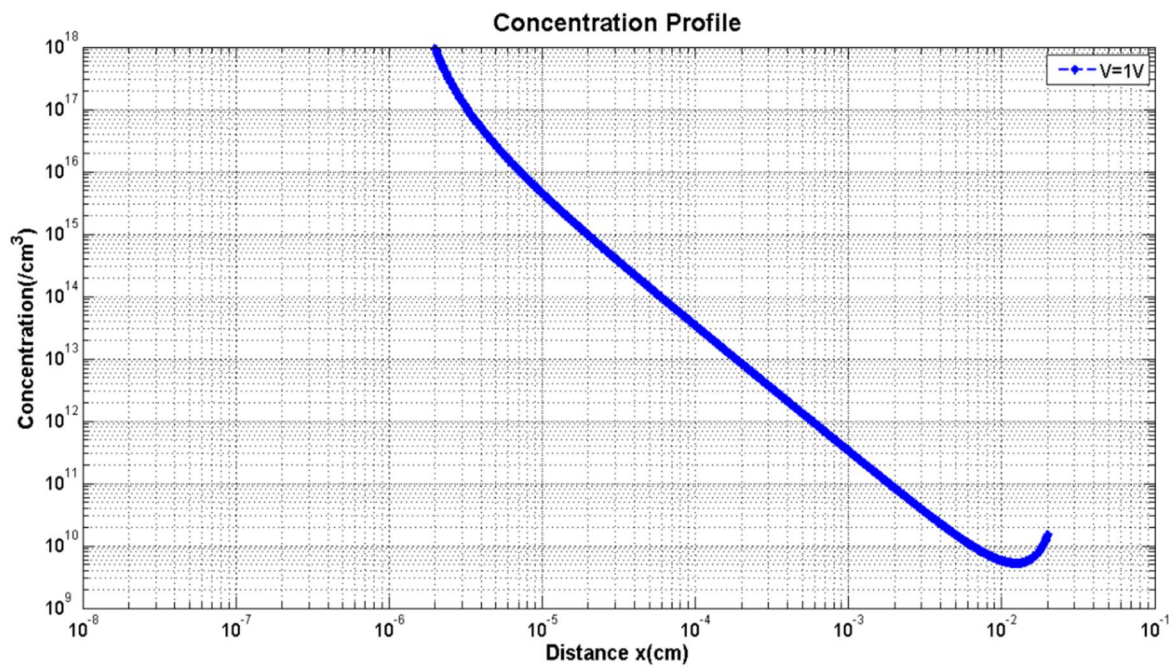
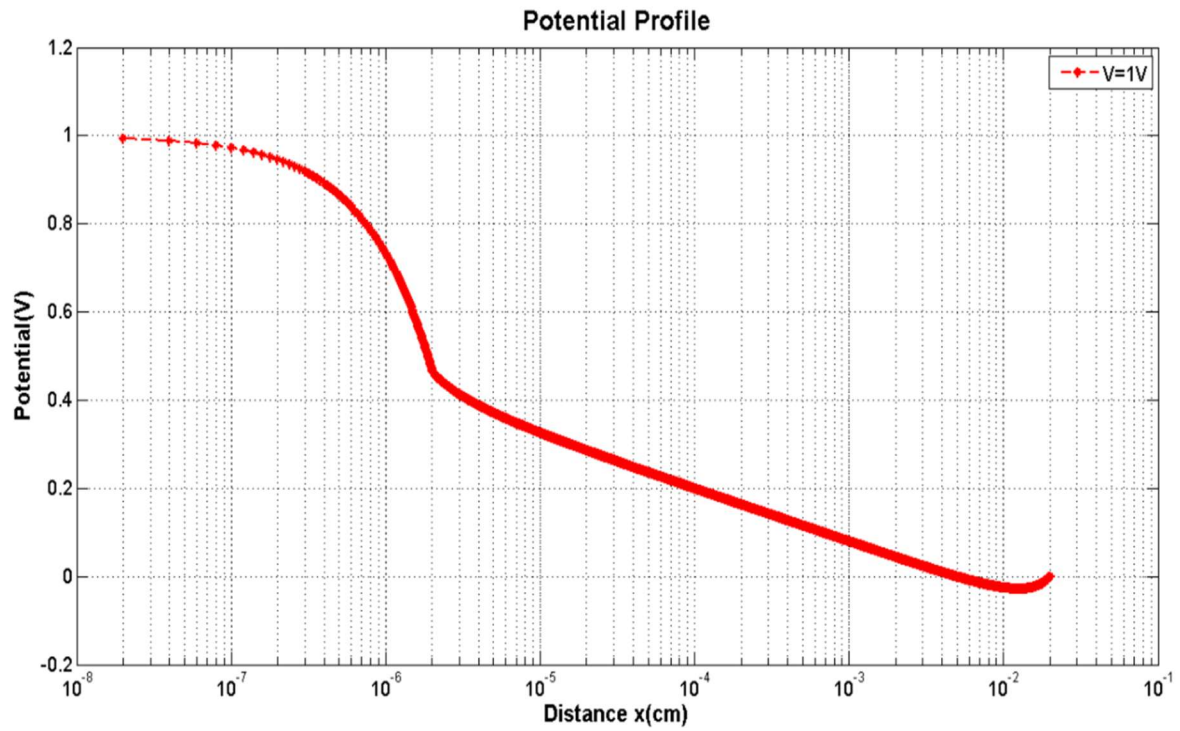


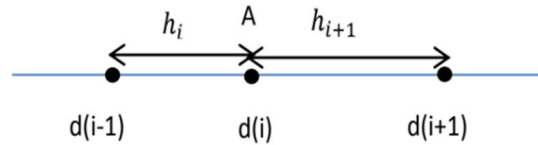
# Solution of problem sheet 5

## Solution f



In this solution we have consider a uniform grid points in oxide and non-uniform grid point spacing in semiconductor.

At point 'A',



Where  $d[i]$ ,  $d[i-1]$ ,  $d[i+1]$  = Position of grid points

Taylor's Series expansion of any function is

$$f(x + h_{i+1}) = f(x) + \frac{f'(x)}{1!} (h_{i+1}) + \frac{f''(x)}{2!} h_{i+1}^2 \dots \text{so on} \dots \dots \dots (1)$$

$$f(x - h_i) = f(x) - \frac{f'(x)}{1!} (h_i) + \frac{f''(x)}{2!} h_i^2 \dots \text{so on} \dots \dots \dots (2)$$

Neglecting higher order terms

Multiply equation (1) and (2) by and respectively and adding them, gives us

$$f''(x) = \frac{f(x + h_{i+1}) * h_i - (h_i + h_{i+1})f(x) + f(x - h_i) * h_{i+1}}{(h_{i+1}^2 * h_i + h_i^2 * h_{i+1})/2}$$

In numerical form,

$$f'' = \frac{f_{i+1} * h_i - f_i * (h_i + h_{i+1}) + f_{i-1} * h_{i+1}}{(h_{i+1}^2 * h_i + h_i^2 * h_{i+1})/2}$$

Now, the Poisson's equation from previous questions is

$$\frac{\partial^2 V_i}{\partial x^2} = \frac{q}{\epsilon} \left( n_i \exp \left( \frac{V_i}{kT} \right) \right)$$

The finite difference form would be

$$\frac{V_{i+1} * h_i - V_i * (h_i + h_{i+1}) + V_{i-1} * h_{i+1}}{(h_{i+1}^2 * h_i + h_i^2 * h_{i+1})/2} = \frac{q}{\epsilon} \left( n_i \exp \left( \frac{V_i}{kT} \right) \right)$$

$$V_{i+1} * h_i - V_i * (h_i + h_{i+1}) + V_{i-1} * h_{i+1} = \frac{q}{\epsilon} * \frac{(h_{i+1}^2 * h_i + h_i^2 * h_{i+1})}{2} * \left( n_i \exp \left( \frac{V_i}{kT} \right) \right)$$

For n cases, the system of equations would look like

$$V_1 = V_a$$

$$V_3 * h_2 - V_2 * (h_2 + h_3) + V_1 * h_3 = \frac{q}{\epsilon} * \frac{(h_3^2 * h_2 + h_2^2 * h_3)}{2} * \left( n_i \exp \left( \frac{V_2}{kT} \right) \right)$$

$$V_4 * h_3 - V_3 * (h_3 + h_4) + V_2 * h_4 = \frac{q}{\epsilon} * \frac{(h_4^2 * h_3 + h_3^2 * h_4)}{2} * \left( n_i \exp \left( \frac{V_3}{kT} \right) \right)$$

... ..

$$V_n = V_b$$

Where are boundary conditions.

Because of 20nm oxide on the semiconductor the function and its jacobian is changed as

following:

$$f(V_1, V_2, \dots, V_N) =$$

$$\left[ \begin{array}{c}
 V_1 - V_a \\
 \epsilon_{ox} * V_3 - 2 \epsilon_{ox} * V_2 + \epsilon_{ox} * V_1 \\
 \epsilon_{ox} * V_4 - 2 \epsilon_{ox} * V_3 + \epsilon_{ox} * V_2 \\
 \vdots \\
 \vdots \\
 \epsilon_{ox} * V_{N1} - 2 \epsilon_{ox} * V_{N1-1} + \epsilon_{ox} * V_{N1-2} \\
 \epsilon_{Si} * V_{N1+1} - (\epsilon_{ox} + \epsilon_{Si}) * V_{N1} + \epsilon_{ox} * V_{N1-1} - \frac{dx^2 * q * n_i * e^{\frac{qV_i}{kT}}}{\epsilon_0} \\
 V_{N1+2} * h_{N1} - V_{N1+1} * (h_{N1} + h_{N1+1}) + V_{N1} * h_{N1+1} - \frac{q}{\epsilon} * \frac{(h_{N1+1}^2 * h_{N1} + h_{N1}^2 * h_{N1+1})}{2} * \left( n_i \exp\left(\frac{V_3}{kT}\right) \right) \\
 \vdots \\
 V_{i+1} * h_i - V_i * (h_i + h_{i+1}) + V_{i-1} * h_{i+1} - \frac{q}{\epsilon} * \frac{(h_{i+1}^2 * h_i + h_i^2 * h_{i+1})}{2} * \left( n_i \exp\left(\frac{V_i}{kT}\right) \right) \\
 V_N - V_b
 \end{array} \right]$$

Oxide-semiconductor boundary equation

So dx= distance between the two grid point in oxide region.

Here N1 grid point is boundary point of oxide layer and semiconductor.

$$Df = \left[ \begin{array}{cccccc}
 1 & 0 & 0 & 0 & ..... & 0 \\
 \epsilon_{ox} & -2 * \epsilon_{ox} & \epsilon_{ox} & 0 & ..... & 0 \\
 0 & \epsilon_{ox} & -2 * \epsilon_{ox} & \epsilon_{ox} & ..... & 0 \\
 0 & 0 & \epsilon_{ox} & G(N1) & \epsilon_{si} & .... \\
 .... & ... & .... & \epsilon_{si} * h(N) & G(N-1) & \epsilon_{si} * h(N-1) \\
 0 & 0 & ..... & ..... & 0 & 1
 \end{array} \right]$$

Oxide-semiconductor boundary equation

Where,  $G(N1) = -(\epsilon_{ox} + \epsilon_{Si}) - \frac{dx^2 * q^2 * n_i * e^{\frac{qV_i}{kT}}}{\epsilon_0 * kT}$

$$G(N-1) = -\epsilon_{Si} * (h_{N-1} + h_N) - \frac{(h_{i+1}^2 * h_i + h_i^2 * h_{i+1})}{2} * \frac{q^2 * n_i * e^{\frac{qV_{N-1}}{kT}}}{\epsilon_0 * kT}$$